



Program-controlled Diffusion Furnace (L4514)



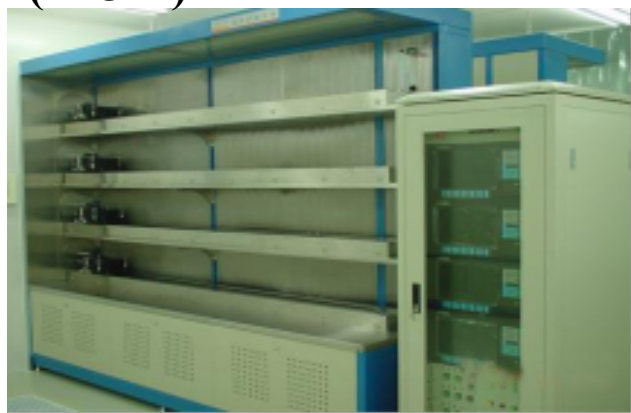
CVD (ET-2000)



PECVD (SI 500D)



FE-SEM (SUPRA 55)



Micro-Control Diffusion Furnace (4473)



LPCVD (F500-6)



PEALD (TFS 200)



Lithography



Magnetron Sputtering System (Qprep 400)



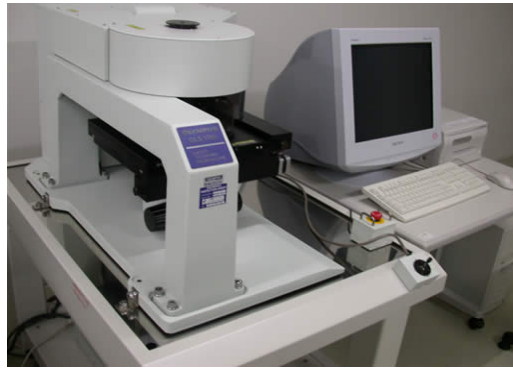
Magnetron Sputtering (Explorer-14)



Mask Aligner (Karl SUSS MA6/BA6)



Silicon Etching (Alcatel AMS 200 SE)



Confocal Laser Scanning Microscope (OLS 1200)



AFM (OXFORD Cypher S)



ICP Etching (SI 500)



Surface Profile Measuring System (Bruker DEKTAK)



Thermal Diffusivity and Conductivity (LFA 467)



CMP (POLI-400M)



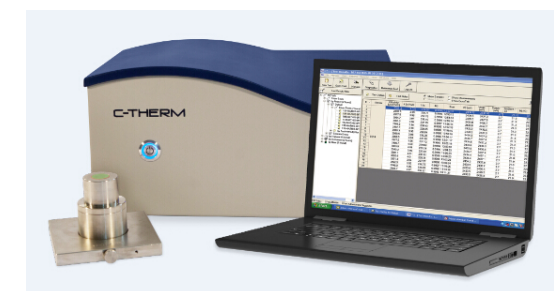
Low-temperature Vacuum Microwave Probe Station (Semishare)



Differential Scanning Calorimeter (DSC 214)



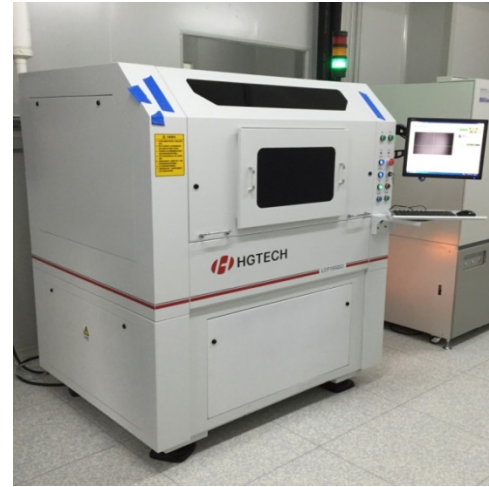
Aligner Wafer Bonder (AML-AWB-04)



Thermal Conductivity Meter (C-THERM TCI)



X-Ray Diffraction (XRD-7000)



Laser Scribing Machine (LCF 150QC)



Confocal Raman Microscopy (ID Spec ARCTIC)



High and Low Temperature Cycling Chamber



Fourier Transform Infrared Spectrometer (Nicolet is10)